

FORM PTO-1449 U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICE

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09/889,307

**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

(Use several sheets if necessary)

37 CFR 1.98(b)

APPLICANT
Xavier Jean-François LEVECO et al.

FILING DATE
November 2, 2001

GROUP
2877

U.S. PATENT DOCUMENTS

EXAMINER INITIAL	PATENT NUMBER	ISSUE DATE	PATENTEE	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
AA						
AB						
AC						
AD						
AE						
AF						

FOREIGN PATENT OR PUBLISHED FOREIGN PATENT APPLICATION

	DOCUMENT NO.	PUBL. DATE	COUNTRY OR PATENT OFFICE	CLASS	TRANSLATION YES
DBE	AI 197 05 119 A1	08/98	DE		YES
	AJ				
	AK				
	AL				
	AM				
	AN				

OTHER DOCUMENTS (Including Author, Title, Date, Relevant Pages, Place of Publication)

DBE	AT	Michael C. Roggemann et al., "Algorithm to Increase the Largest Aberration that Can be Reconstructed from Hartman Sensor Measurements," <u>APPLIED OPTICS</u> , v. 37, 1998, PP. 4321-4329.
	AU	
	AV	
	AW	

EXAMINER

D. Benzel

DATE CONSIDERED

2/2/04

EXAMINER: Initial citation considered. Draw line through citation if not in conformance and not considered.
Include copy of this form with next communication to applicant.